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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re: Application of Cerni et al.
Serial No.: 09/296,928
Filed: April 22, 1999

Examiner: Not Assigned
Group Art Unit: 2877
Docket No.: 7009/018CP

CHEMICAL MECHANICAL
PLANARIZATION (CMP) SLURRY
QUALITY CONTROL PROCESS AND
PARTICLE SIZE DISTRIBUTION
MEASURING SYSTEMS



CERTIFICATE OF MAILING (37 CFR 1.8)

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, DC 20231.

September 13, 1999
Date

Nancy Halas
Nancy Halas

Assistant Commissioner for Patents
Washington, DC 20231

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Pursuant to 37 CFR §1.97(c) and the duty of disclosure under 37 CFR §1.56, Applicant(s) submit the enclosed references and Form 1449 for consideration in the above-identified application.

The undersigned attorney believes that no fees are due, but authorizes the Commissioner to charge any additionally required fees to Deposit Account No. 04-1697.

Respectfully submitted,
DUFT, GRAZIANO, & FOREST, P.C.

By:

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